

SEISMIC

Sophisticated MEMS capacitive sensors combined with advanced electronics are replacing traditional geophones or seismometers for different types of seismic measurements.

Numbers of applications outside the traditional strong motion earthquake monitoring are using these seismic motion sensors for their extreme low noise, high resolution and large dynamic range. These applications are characterized by low amplitude signals produced by natural (earthquake, volcano, subsidence or even wind) or human-induced (explosions, shock, constructions) movements.









SF1600SN.A

(no oscillator)

±3g

0.3

>1500



SF3600



SF3006

PCB
(24.4mm x 24.4mr

0.9

>1000

PUB		
(24.4mm	Χ	24.4mm)

(24.4mm x 24.4mm)

3 axis (80mm x 80mm x 57mm)

3 axis (80mm x 80mm x 57mm)

SF2006SN.A Product name (no oscill Full scale ±5g

llator)	5F10005.		
	± 3g		
	0.3		

	± (
	0.3

3g ±5g 0.9 >1500 >1000

Description

Noise in µg/√Hz

Bandwidth in Hz

SiFlex[™] accelerometers are the best in class MEMS capacitive products for strong motion seismic and low amplitude vibration sensing with real sub-milli g noise performances.

>1500

SiFlex™ products

3 axis combination of 3 axis combination of SiFlex™ products